Course No.					Course T	itle	Special issue on radiation					
	459.571	1 Le	cture No.	001	(Subtitle	e)	engineerin er	g (radiation ngineering)	(radiation source neering)		3	
Representative Instructor	Name	Kyoung	g-Jae Chun	g (post	: Asso. Pro	of.)	Homepage					
	E-mail jkjlsh1@snu.ac.kr						Phone No.	02-880-8338				
	Interview Time/Place :											
Attachment	(Korean)											
	(English)										
Prerequisite Course	Electromagnetics, Radiation Engineering, Fundamentals of Plasma											
*1.Purpose of Course	This lecture deals with radiation sources that generate artificial radiation. In particular, it will improve the understanding of the generation and transport of charged particle beams, and the generation of electromagnetic radiation via beam-cavity interaction, which is a core element technology of radiation generating devices.											
*2.Materials and Reference	[Main text] Stanley Humphries, Jr., Charged Particle Beams (2002). Stanley Humphries, Jr., Principles of Charged Particle Acceleration (1999). [Reference] H. Zhang, Ion Sources (1999). Ian G. Brown, The Physics and Technology of Ion Sources (1989). Syed Naeem Ahmed, Physics & Engineering of Radiation Detection, 2nd ed. (2015).											
*3.Evaluation Method	Attendand	ce Ta	sk Me	dium	Final	Ran	ndom Evaluation	Attitude	Other	1	otal	
		10	10	40	40		0	0		0	0	
	Remark	of Othe	rs									
*4.Lecture Plan	 Radiation sources Neutron sources Elementary ion sources Basic properties of plasmas Gas discharge fundamentals Gas breakdown and gas-filled detectors Phase-space description of charged particle beams Beam emittance Beam-generated forces Electron guns Extraction systems for ion sources High-power pulsed electron and ion diodes Paraxial beam transport with space charge Ion beam neutralization Generation of radiation with electron beams 											
5.References to Course Registration												
6. Support Services for Students with	For Lec	tures										
	For Assign	nments ations										
Disabilities	Othe	ers										

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